AMENDMENTS TO THE CLAIMS:

Please cancel claims 15, 27, and 28 without prejudice or disclaimer of their subject matter, and amend claims 13, 20, 21, and 26, as indicated below. This listing of claims will replace all prior versions and listings of claims in the application:

LISTING OF CLAIMS:

1.-12. (Cancelled)

13. (Currently Amended) A method for manufacturing a mold tool adapted to be used for forming a structured nano scale pattern on an object and having a layer, which is anti-adhesive with regard to the object, said method comprising the following steps:

providing a stamp blank with a structured pattern on a surface,

depositing a layer of a metal <u>chosen from titanium</u>, <u>zirconium</u>, <u>niobium</u>, <u>tantalum</u>, <u>and aluminium</u>, <u>and mixtures thereof</u>, on the patterned surface, said metal having a stable oxidation number-and being capable of forming a mechanically stable oxide film,

oxidising the layer of metal to form [[an]] a mechanically stable oxide film, and applying at least one reagent on the oxide film, said reagent comprising molecule chains, each having a linkage group, which is chemically bonded with the oxide film, wherein the molecule chains either from the beginning comprise at least one group comprising fluorine, or are provided with at least one such group in a subsequent treatment.

14. (Previously Presented) The method of claim 13 wherein said linkage group is chemically bonded by a covalent bond with said oxide film.

15. (Cancelled)

16. (Previously Presented) The method according to claim 13, wherein said linkage

group is chosen among silane groups, phosphate groups and carboxylic groups.

17. (Previously Presented) The method according to above claim 13, wherein the metal

is furnished to the pattern equipped surface in an evaporated form.

18. (Previously Presented) The method according to above claim 13, wherein the layer

of metal is oxidised by bringing it in contact with a gas comprising oxygen, such as surrounding

air, filtered surrounding air, or a synthetical gas mixture comprising oxygen.

19. (Previously Presented) The method according to claim 13, wherein the patterned

surface is coated with a layer of metal with a thickness (HT) of 1-300 nm.

20. (Currently Amended) The method according to any one of claims 13-17 13, 14, 16,

and 17, wherein the patterned surface is coated with a layer of metal with a thickness (HT) of 1-

100 nm.

21. (Currently Amended) A mold tool adapted to be used for forming a structured nano

scale pattern on an object, and having a layer, which is anti-adhesive with regard to the object,

said mold tool comprising:

a stamp blank[[,]] having a structured pattern on its surface, [[and]]

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[[a]] an anti-adhesive layer-of a metal, which is anti-adhesive with regard to the object,

having a stable oxidation number and being capable of forming a mechanically stable oxide film,

which layer of metal has been applied on said surface and thereafter brought to oxidise to form a

mechanically stable oxide film, wherein the anti-adhesive layer comprises comprising molecule

chains, each having at least one linkage group and at least one group comprising fluorine, and

a layer of metal disposed intermediate to the stamp blank and the anti-adhesive layer, the

layer of metal comprising at least one of aluminium, zirconium, tantalum, niobium, and titanium,

the layer of metal being oxidised to form a mechanically stable oxide film to which by chemical

bonding are bonded with the oxide film, and the at least one linkage group comprising fluorine is

chemically bonded.

22. (Previously Presented) The mold tool according to claim 21 wherein said at least

one linkage group is chemically bonded by a covalent bond with said oxide film.

23. (Previously Presented) The mold tool according to claim 21, wherein said layer of

metal has a thickness (HT) of 1-300 nm.

24. (Previously Presented) The mold tool according to claim 21, wherein said layer of

metal has a thickness (HT) of 1-100 nm.

25. (Previously Presented) The mold tool according to claim 21, wherein said stamp

blank comprises a metal and/or silicon.

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26. (Currently Amended) The mold tool according to claim 25, wherein said stamp blank is a nicellic stamp blank comprises nickel.

27.-28. (Cancelled)